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2.5D Finite Element Method for Electrical Impedance Tomography Considering the Complete Electrode Model

Navid Bahrani, Andy Adler

System and Computer Engineering

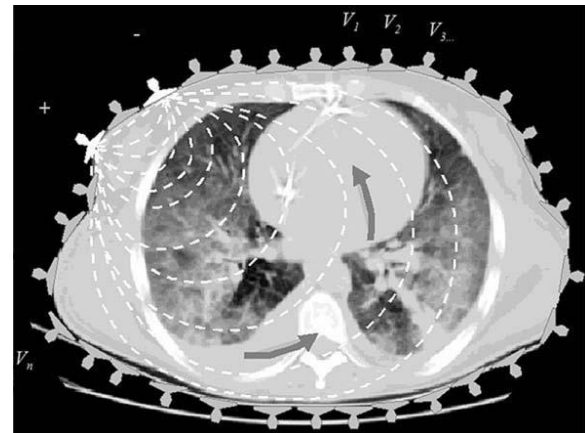
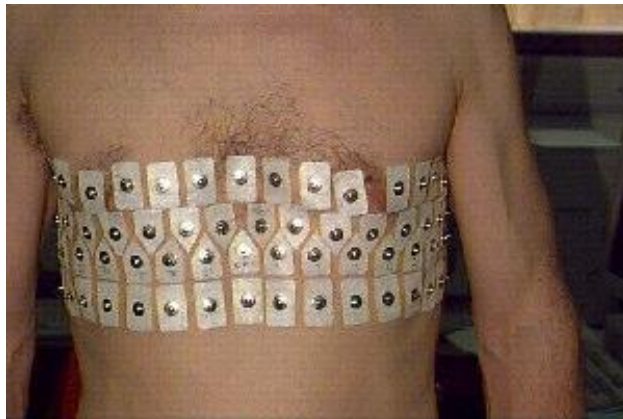
Carleton University

CCECE 2012

April 30, 2012

Electrical Impedance Tomography (EIT)

- EIT is used to generate images of the internal structure of sections of a body
- The EIT problem is
 - to reconstruct an unknown impedance distribution from boundary measurements.



Photos: (left) from Wikipedia/EIT, (right) from [4]

The EIT Problem

- Forward Model (2D & 3D)

$$\nabla_{2D} \cdot (\sigma(x,y) \nabla_{2D} \varphi(x,y)) = 0$$

$$\nabla_{3D} \cdot (\sigma(x,y,z) \nabla_{3D} \varphi(x,y,z)) = 0$$

$$\sigma \frac{\partial \phi}{\partial n} = \begin{cases} J & \text{on current electrodes} \\ 0 & \text{elsewhere on the surface} \end{cases}$$

- Finite Element Method
- Current Patterns
- Electrode Models

2½D Motivation

- The 3D FE Model recruits too much elements.
 - => requires much more memory and **Computational Complexity** vs. 2D
 - Both Forward and Inverse Problem
 - Specially the inverse part
 - Requires more calculation time
 - ≠ Real time
 - Or a super-computer for fast imaging
 - ≠ Portability and Inexpensiveness

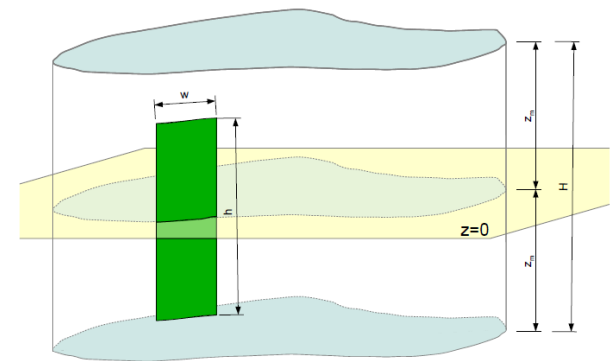
The 2½D Model

- Assumption
 - Translational Invariance along z
 - => Symmetric Voltages
- Equations

$$\nabla_{3D} \cdot (\sigma(x, y, z) \nabla_{3D} \varphi(x, y, z)) = 0$$

$$\varphi(x, y, z) = \sum_{k=0}^{\infty} V_k(x, y) \cos\left(\frac{k\pi}{a} z\right)$$

$$\begin{cases} \nabla_{2D} \cdot (\sigma(x, y) \nabla V_k(x, y)) - \sigma(x, y) \left(\frac{k\pi}{a}\right)^2 V_k(x, y) = 0 \\ \sigma(x, y) \frac{\partial}{\partial n} V_k(x, y) = J_k \end{cases}$$

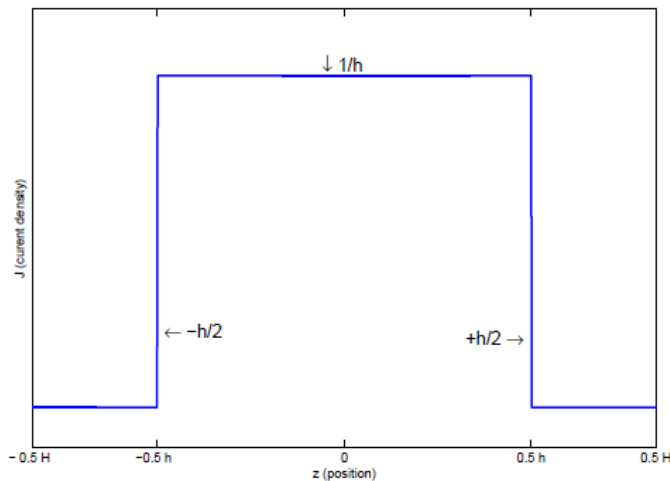


Boundary Condition $\sigma(x, y) \frac{\partial V_k}{\partial n} = J_k$

- for $I = 1$

$$J_0 = \frac{1}{H} = \frac{1}{2a}$$

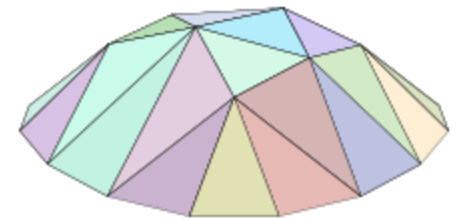
$$J_k = \frac{2}{k\pi h} \sin\left(\frac{k\pi h}{2a}\right)$$



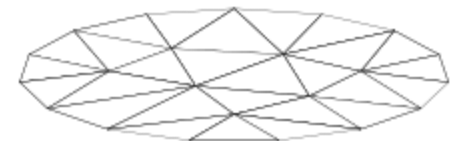
Finite Element Method

- Interpolation functions, i.e. basis

$$\tilde{u}_n(\vec{x}) = \sum_{i=1}^M u_i^n \phi_i(\vec{x})$$



- The Modified '*Stiffness Matrix*'



$$S'_{ij}{}^k = S_{ij}^k + \left(\frac{n\pi}{a}\right)^2 R_{ij}^k = \int_{E_k} \nabla\phi_i \cdot \nabla\phi_j + \left(\frac{n\pi}{a}\right)^2 \phi_i\phi_j d\Omega$$

$$S'(n)U_n = I_n$$

Inverse Problem of EIT

- Static EIT, Difference EIT
- Jacobian (Sensitivity Matrix)

$$z = \Delta v = v_{\sigma_2} - v_{\sigma_1}$$

$$z = \mathbf{J}x + n$$

$$x = \Delta\sigma = \sigma_2 - \sigma_1$$

$$\mathbf{J} = T \left[-\frac{\partial}{\partial\sigma} S^{-1}(\sigma)I \right] = T \left[S^{-1}(\sigma) \frac{\partial}{\partial\sigma} S(\sigma) S^{-1}(\sigma)I \right]$$

$$\hat{x} = (\mathbf{J}^T \mathbf{J})^{-1} \mathbf{J}^T z$$

$$\hat{x} = (\mathbf{J}^T \mathbf{J} + \lambda^2 \mathbf{R}^T \mathbf{R})^{-1} \mathbf{J}^T z = Bz$$

Inverse Problem in 2½D

- Using Jacobian:

- For each $n \rightarrow \Delta v_n$

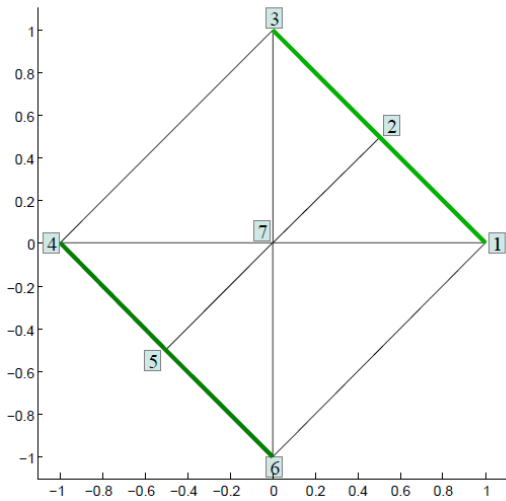
- $n \rightarrow S_n \rightarrow J_n \rightarrow \Delta\sigma_n$

$$\Delta v_n = J_n \Delta\sigma$$

$$J = \sum_{n=0}^{\infty} J_n$$

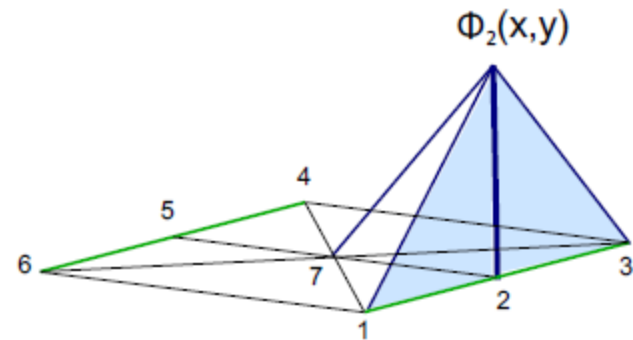
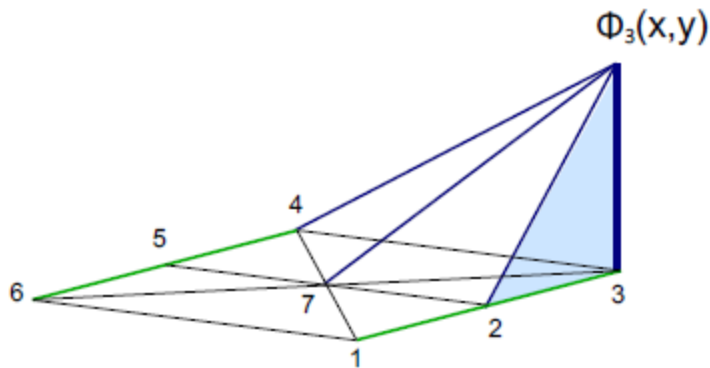
$$\Delta v = \sum_{k=0}^{\infty} \Delta v_k \cos\left(\frac{k\pi}{a} z\right)$$

Complete Electrode Model

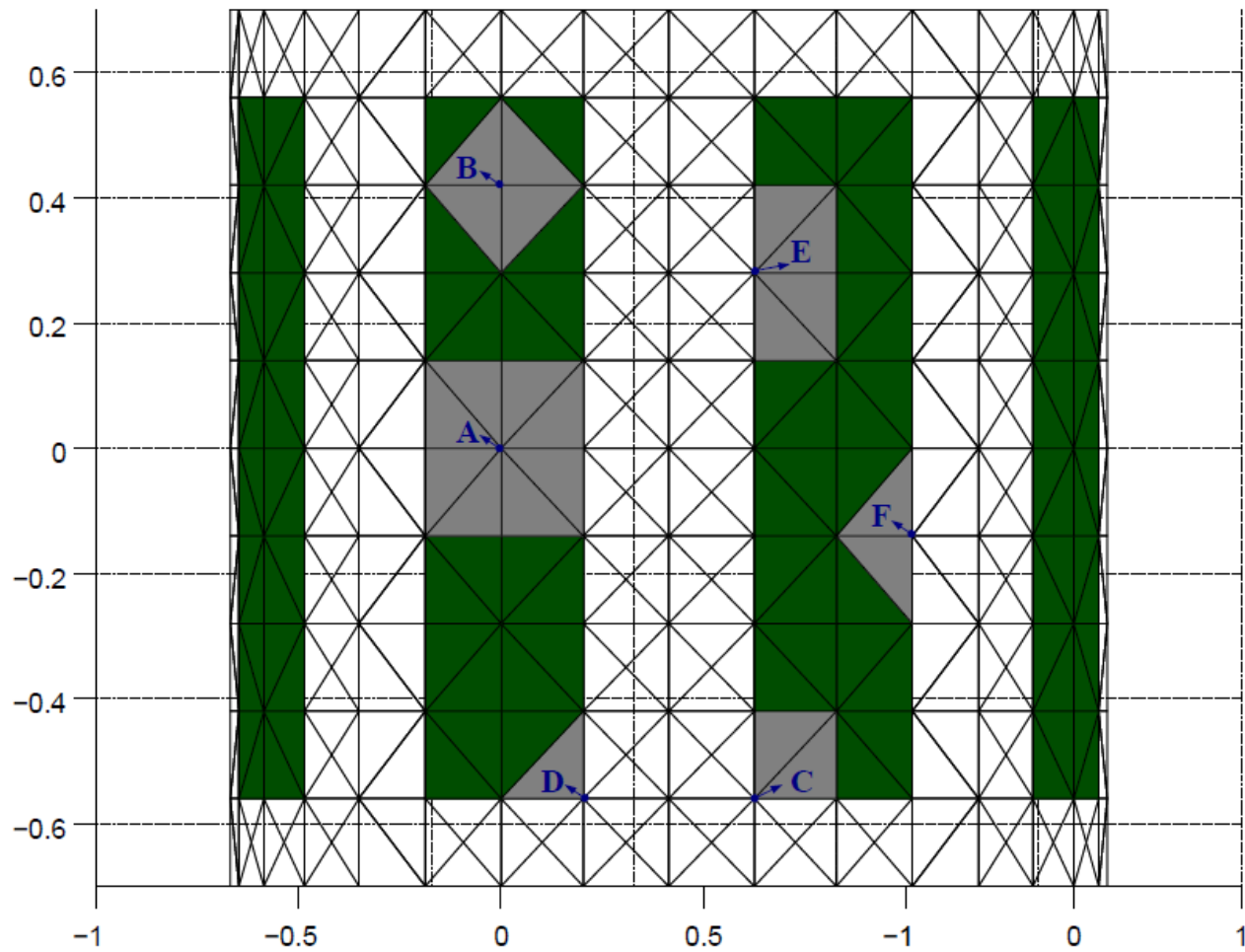


$$\begin{bmatrix} A_M + A_Z & A_W \\ A_W^T & A_D \end{bmatrix} \begin{bmatrix} U \\ V \end{bmatrix} = \begin{bmatrix} \mathbf{0} \\ I \end{bmatrix}$$

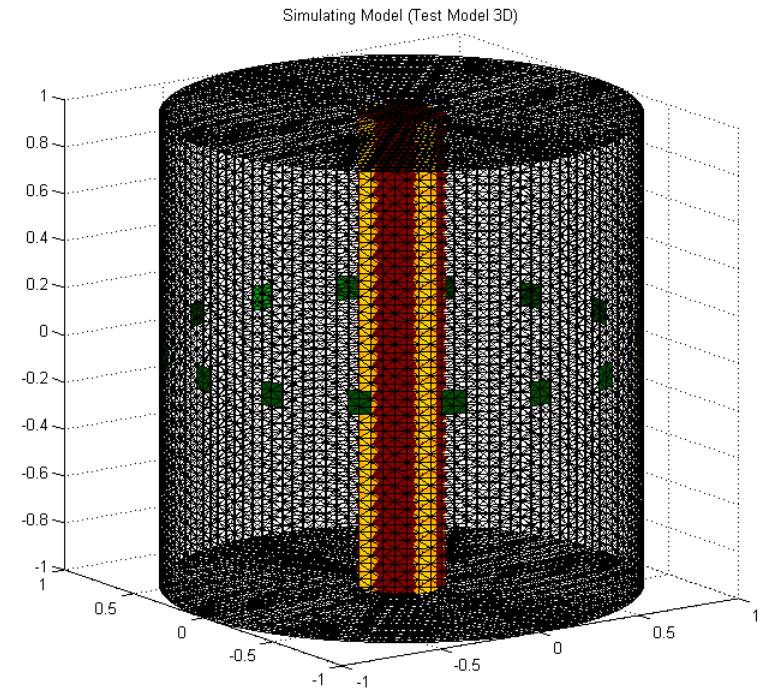
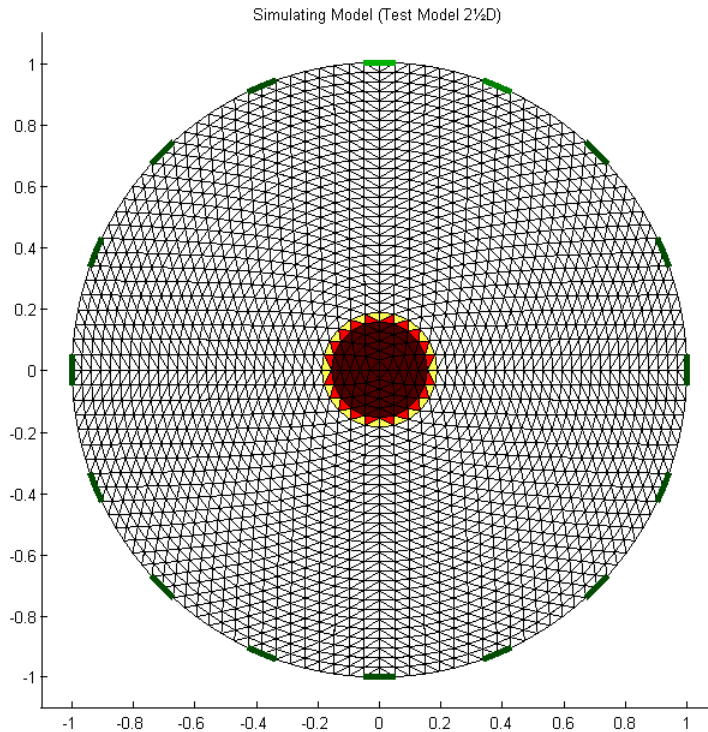
$$A_W = \begin{bmatrix} -\frac{\Delta}{2z_c} & -\frac{\Delta}{z_c} & -\frac{\Delta}{2z_c} & 0 & 0 & 0 & 0 \\ 0 & 0 & 0 & -\frac{\Delta}{2z_c} & -\frac{\Delta}{z_c} & -\frac{\Delta}{2z_c} & 0 \end{bmatrix}^T$$



3D CEM



Mesh



2D mesh with 4096 elements used for the 2½D method (32 layers in xy)

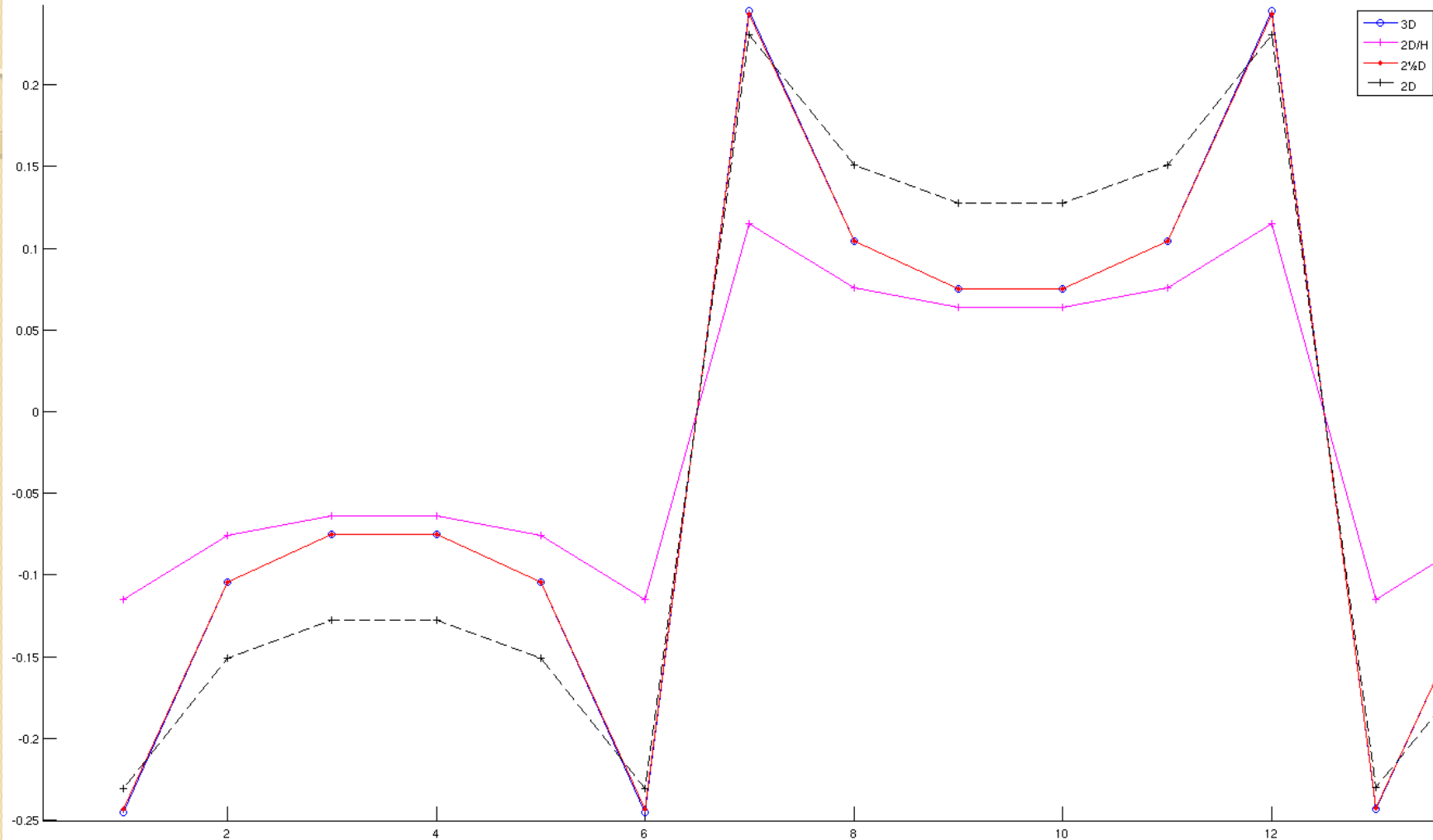
3D mesh with 737,280 elements (61 layers in z)

$H=2$; $h=0.1$, $w \approx 0.1$

The Images are produced by EIDORS

Results for Measurements

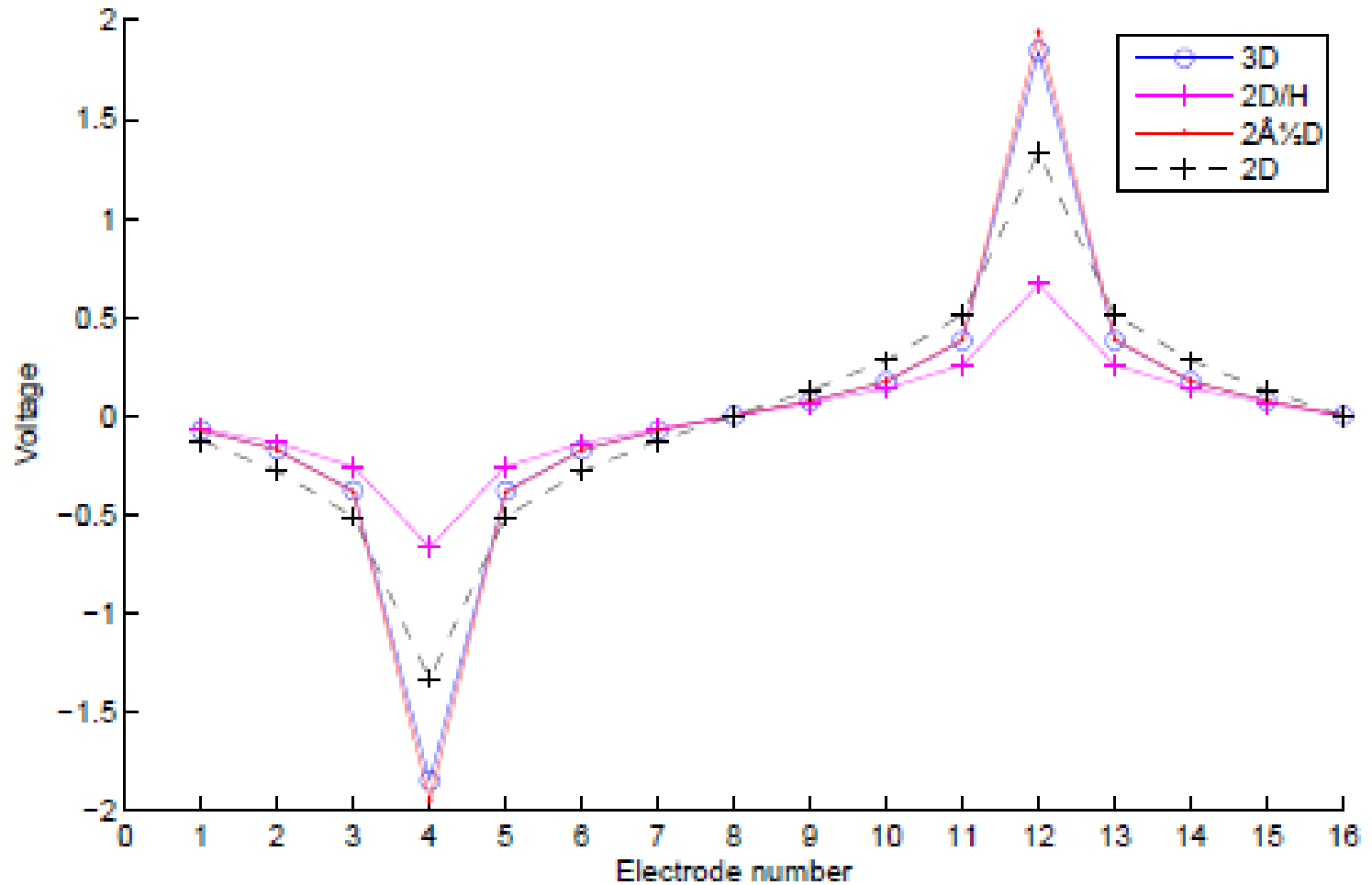
Tank height: 2, Object height: 2, Elect height: 0.1, Elect width: 0.098165, Domain height: 2, MAX_w: 4



Measurements (Difference Voltage of Electrodes) – Opposite Pattern - Only first 5 terms

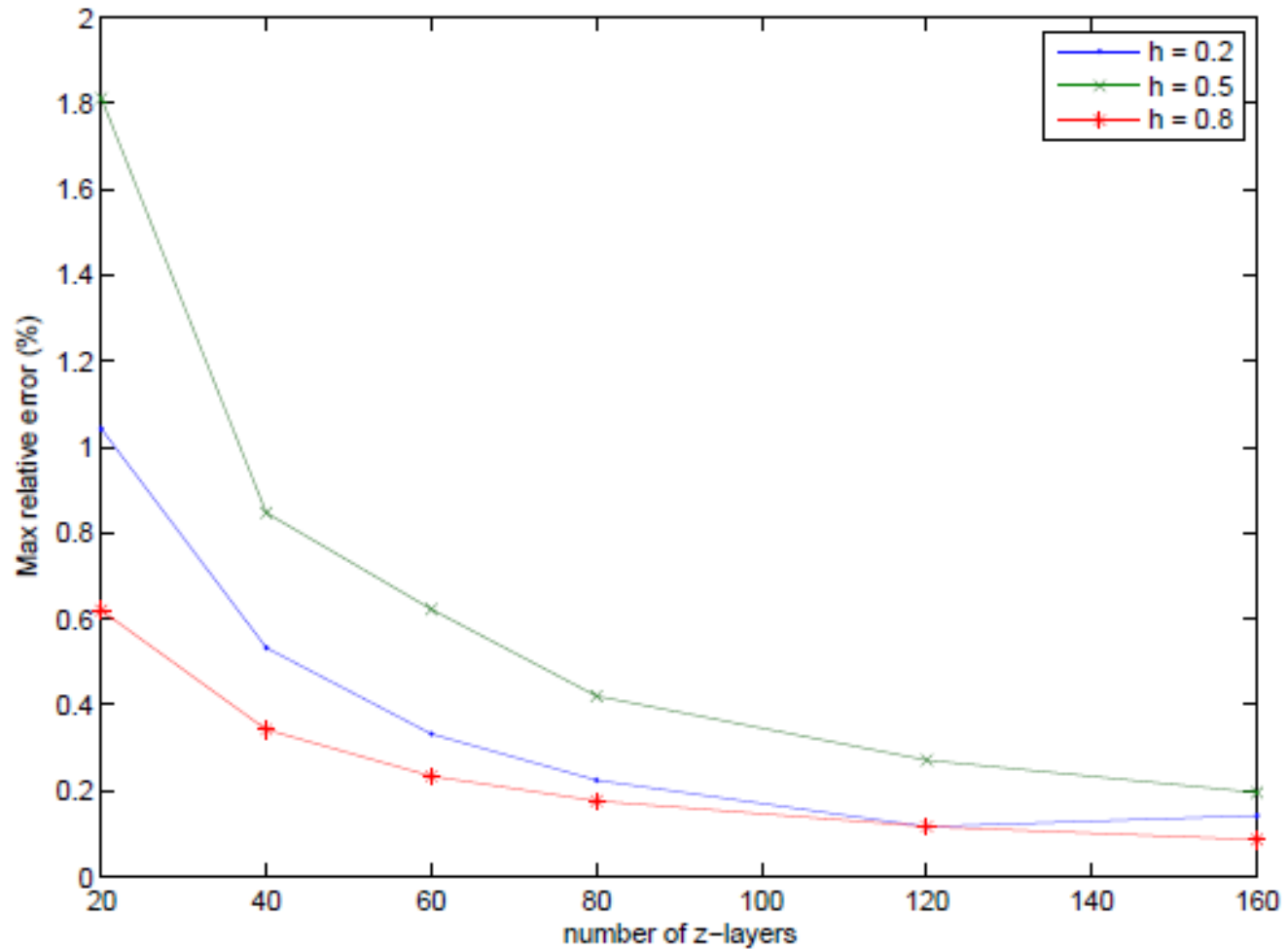
Maximum error: 0.82% (0.002)

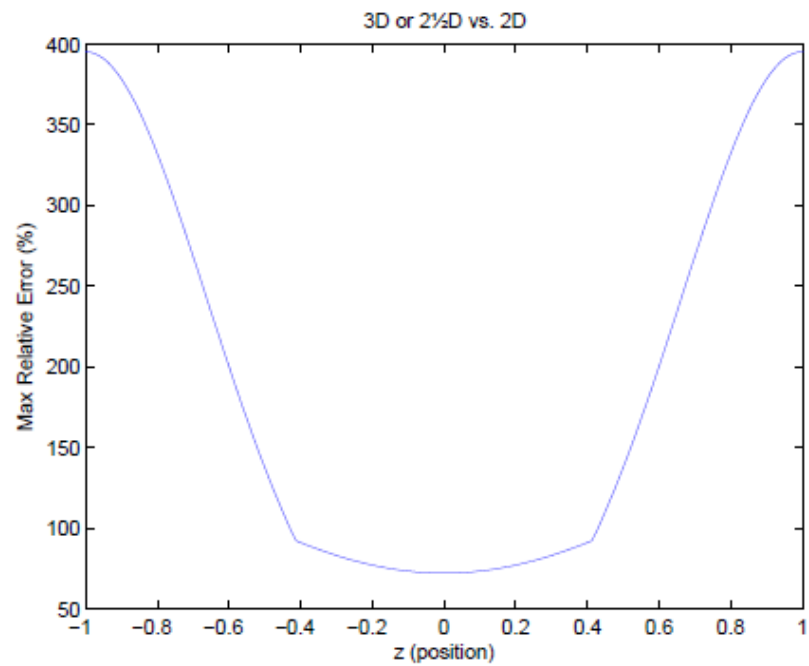
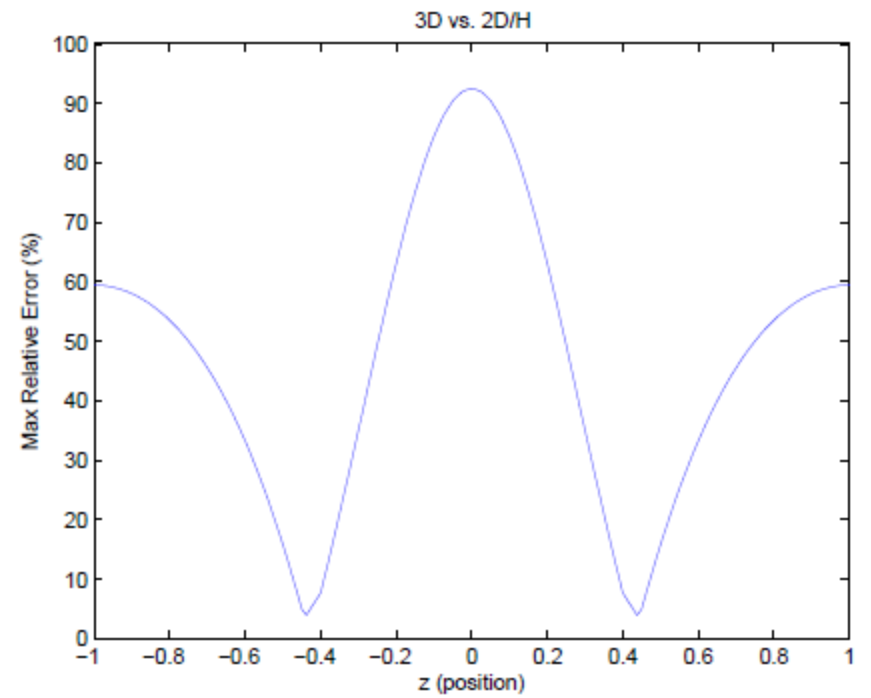
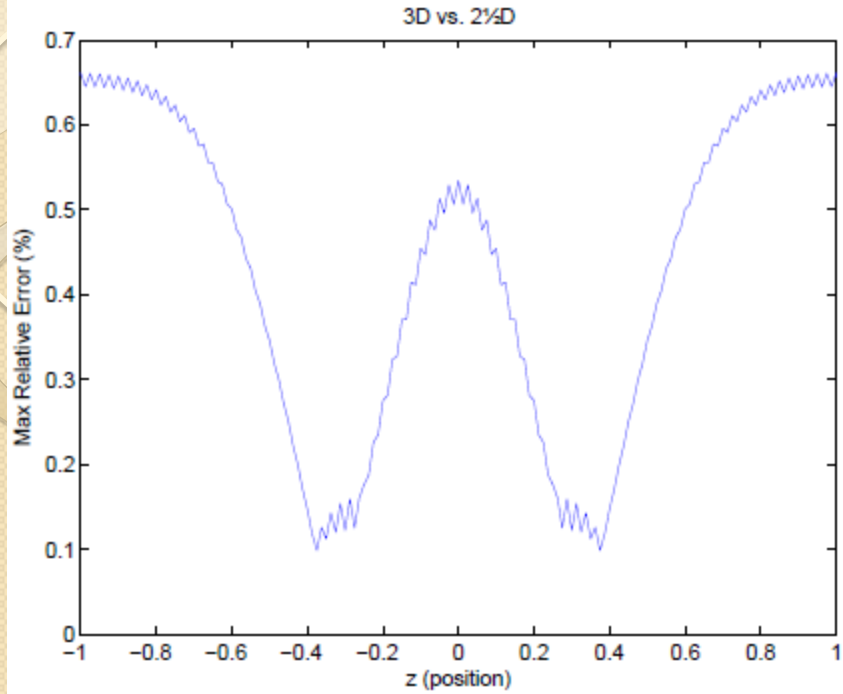
Tank height: 2, Object height: 2, Elect height: 0.4, Elect width: 0.098185, Domain height: 2, $MAX_N: 50$



Comparing 3D, 2D, 2D/H (first term of 2 1/2 D) and 2 1/2 D CEM solutions for electrode voltages - CEM ($W = 0.1, H = 2, h = 0.4$)

Decrement of the Error by Decrement of the Element size

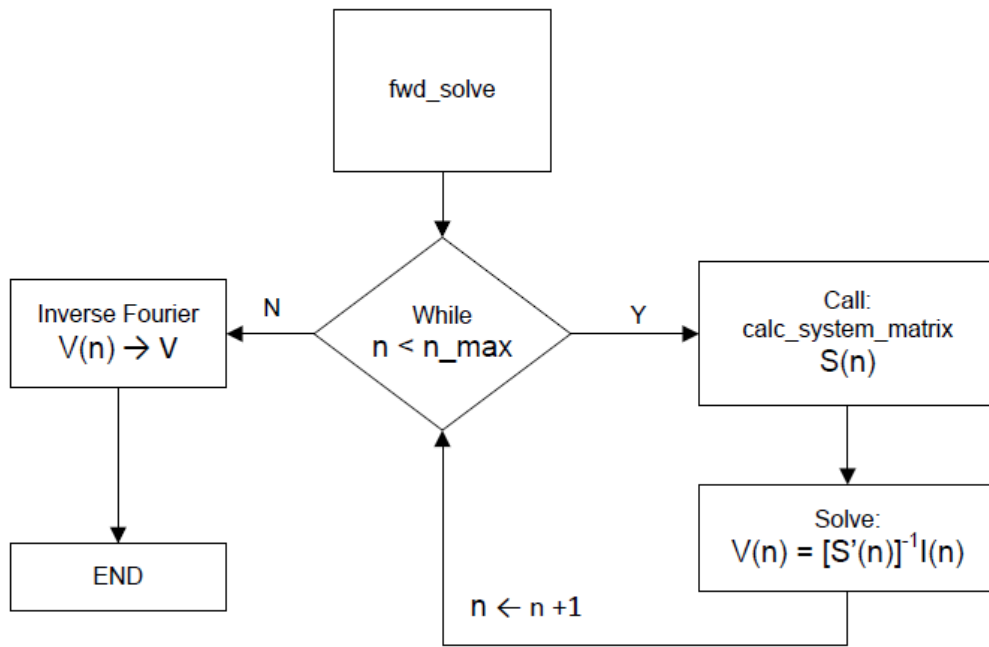




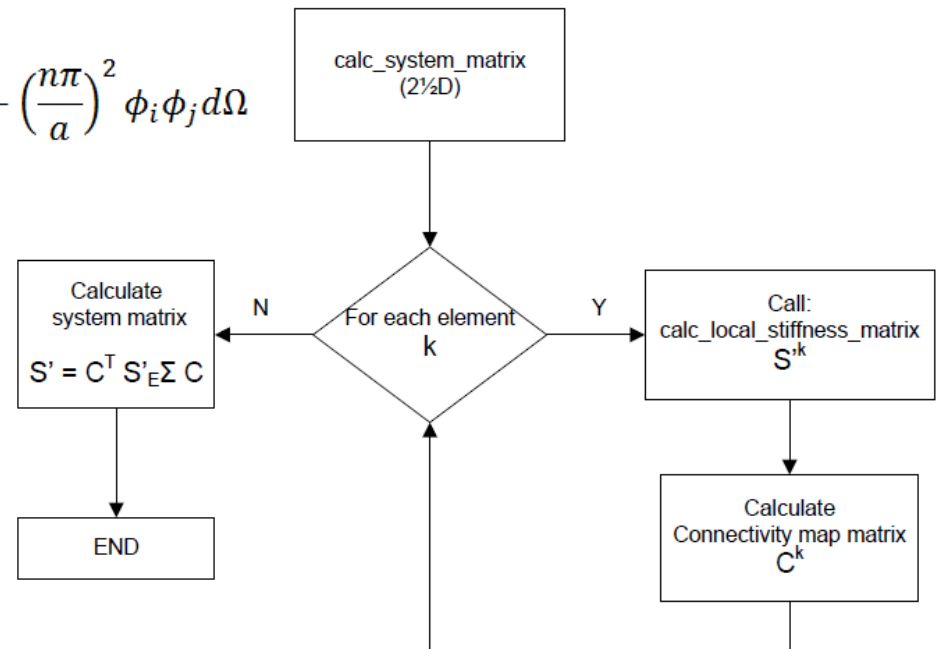
Truncation Point

$$V_{2\frac{1}{2}D} = \frac{1}{H}S^{-1}I + \sum_{n=1}^{\infty} \frac{2}{n\pi h} \sin\left(\frac{n\pi h}{2z_m}\right) \cos\left(\frac{n\pi}{z_m}z\right) \left(S + \left(\frac{n\pi}{z_m}\right)^2 R\right)^{-1} I$$

$\frac{H}{r}$	2		4		10	
	$\frac{h}{H}$	n_{max}	$\frac{h}{H}$	n_{max}	$\frac{h}{H}$	n_{max}
	(0.025, 0.05, 0.1)	3	(0.025)	7	(0.025)	13
	(> 0.1)	2	(0.05)	6	(0.05)	11
			(0.1)	5	(≥ 0.1)	7
			(≥ 0.2)	3		



$$S'_{ij}{}^k = S_{ij}^k + \left(\frac{n\pi}{a}\right)^2 R_{ij}^k = \int_{E_k} \nabla\phi_i \cdot \nabla\phi_j + \left(\frac{n\pi}{a}\right)^2 \phi_i\phi_j d\Omega$$



Time/Memory Performance

$$t_{2\frac{1}{2}D} = t_{2D} + n_{max} \times t_{2D\text{-size Forward_Solve}} + t_R + t_{IFT}$$

Mesh Structure:

$$[2\frac{1}{2}D : Mesh.Nodes]_{N \times 2} \quad \text{vs.} \quad [3D : Mesh.Nodes]_{MN \times 3}$$

$$[2\frac{1}{2}D : Mesh.Elements]_{K \times 3} \quad \text{vs.} \quad [3D : Mesh.Nodes]_{3(M-1)K \times 4}$$

2D: 2,113 nodes and 4,094 elements

if M = 61 slices

3D: 128,893 nodes and 736,920 elements

System Matrix:

$$[S_{2\frac{1}{2}D}]_{N \times N} \quad \text{vs.} \quad [S_{3D}]_{MN \times MN}$$

$$M^2 = 61 \times 61 = 3,681$$

Matrix Inversion at the Forward Problem:

$$[S_{2\frac{1}{2}D}^{-1}]_{N \times N} \quad \text{vs.} \quad [S_{3D}^{-1}]_{MN \times MN}$$

$$M^2 = 61 \times 61 = 3,681$$

The EIDORS Project



- <http://eidors3d.sourceforge.net/>
- ***Electrical Impedance and Diffuse Optical Tomography Reconstruction Software***
- A collaborative project where many groups working on EIT are involved around the world
- Modular-Based structure
- Medical & Industrial Applications

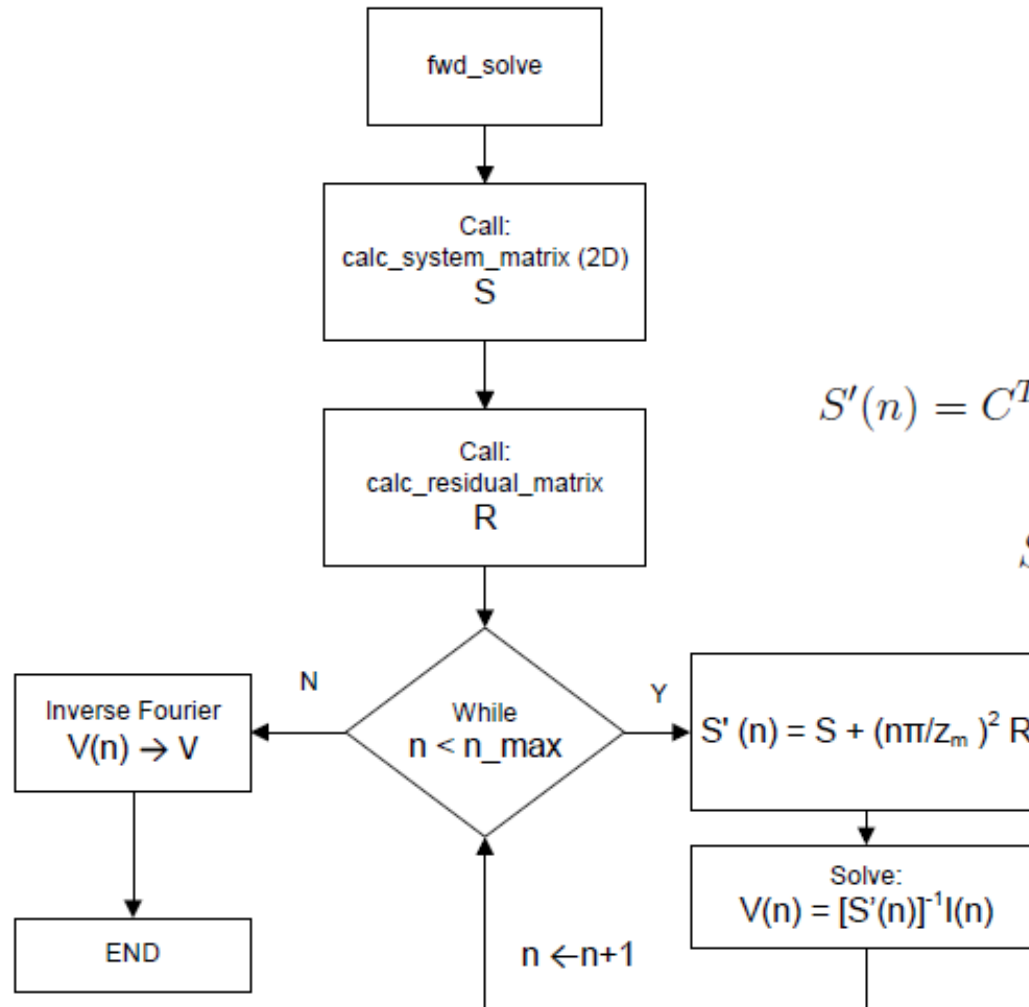
Questions

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Reference

- [0] Ider *et al*, *Electrical impedance tomography of translationally uniform cylindrical objects with general cross-sectional boundaries*. *IEEE Trans. Med. Imaging* 9 49–59, 1990.
- [1] Lionheart W R B, *Uniqueness, shape and dimension in EIT*, *Ann. NY Acad. Sci.* 873 466–71, 1999
- [2] K Jerbi, W R B Lionheart, *et al* *sensitivity matrix and reconstruction algorithm for EIT assuming axial uniformity*, *Physiol. Meas.* 21 (2000) 61–66
- [3] David Holder, *Electrical impedance tomography: methods, history, and applications*, 2004
- [4] Costa E.L.V., Lima R. Gonzalez, Amato M.B.P., “Electrical Impedance Tomography”, *Yearbook of Intensive Care and Emergency Medicine*, 2009.
- [6] ...

Speed/Computation Improvement



$$R = C^T R_E \Sigma C$$

$$R_{ij}^k = \int_{E_k} \phi_i \phi_j d\Omega$$

$$S'(n) = C^T S_E \Sigma C + \left(\frac{n\pi}{z_m}\right)^2 (C^T R_E \Sigma C)$$

$$S'(n) = S + \left(\frac{n\pi}{z_m}\right)^2 R$$

